

Advanced Readout CMOS Architectures with Depleted Integrated sensor Arrays

## First characterization results of ARCADIA FD-MAPS after x-ray irradiation

Coralie Neubüser, T. Corradino, G-F. Dalla Betta, S. Matiazzo, L. Pancheri  
on behalf of the ARCADIA collaboration

29/06/2022

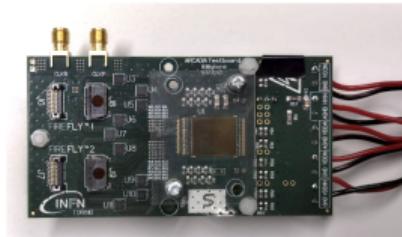
23nd International Workshop on Radiation Imaging Detectors

# ARCADIA main demonstrator characterisation

analysis currently ongoing...

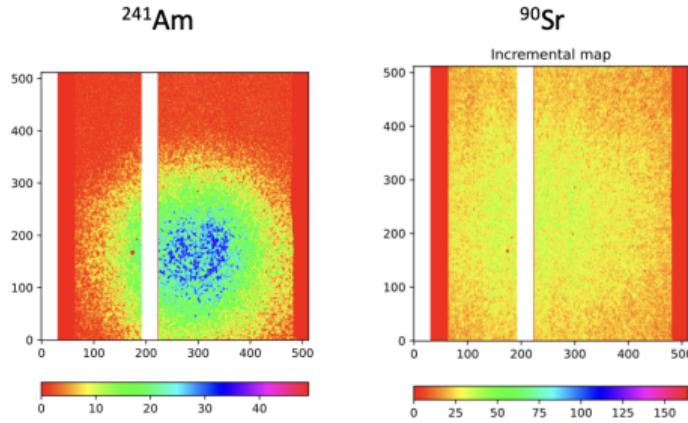


Trento Institute for  
Fundamental Physics  
and Applications

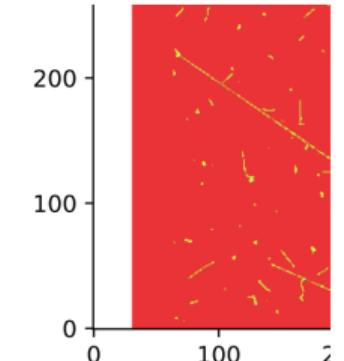
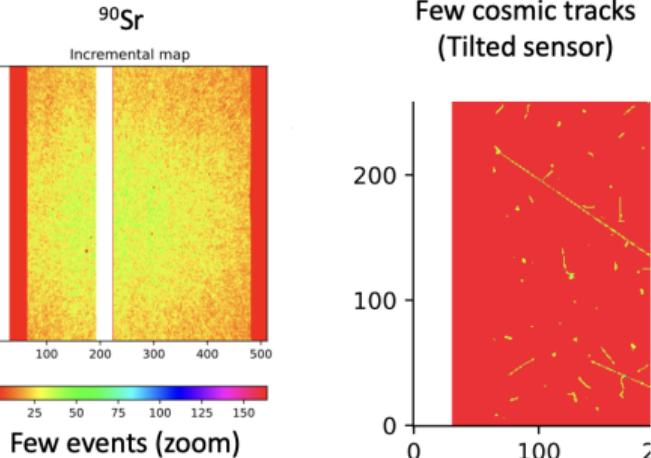
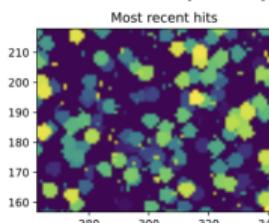


110 nm CMOS CIS technology,  
high-resistivity bulk, operated  
in full depletion mode

Pixel size =  $25 \times 25 \mu\text{m}^2$   
Matrix =  $512 \times 512$   
Thickness =  $200 \mu\text{m}$



Few events (zoom)

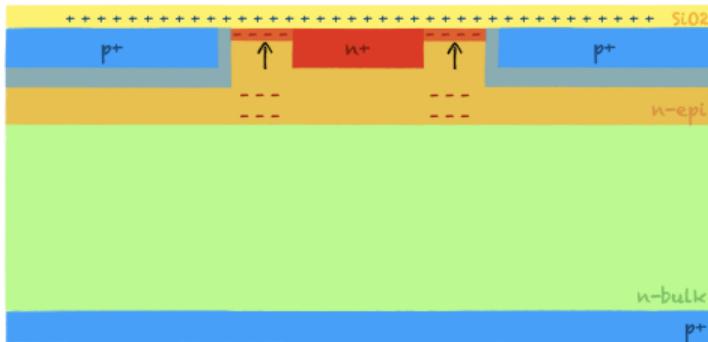


...more results are coming soon.

# Introduction



Trento Institute for  
Fundamental Physics  
and Applications



capacitance at nwell is input  
capacitance to readout chain  
thus impacts noise of chip

- ▶ started investigation of impact of oxide charges on pixel capacitance in 2020 in simulations (different pixel designs for ARCADIA engineering runs)  
[1] [C. Neubüser et al., *Sensor design optimization of innovative low-power, large area MAPS for HEP and applied science*, in *Frontiers in Physics* Vol. 9 2021, doi:10.3389/fphy.2021.625401]
- ▶ presented impact of X-ray irradiation on SEED (predecessor of ARCADIA) samples at iWorld 2021  
[2] [C. Neubüser et al., *Impact of X-ray induced radiation damage on FD-MAPS of the ARCADIA project*, 2022 *JINST* 17 C01035]

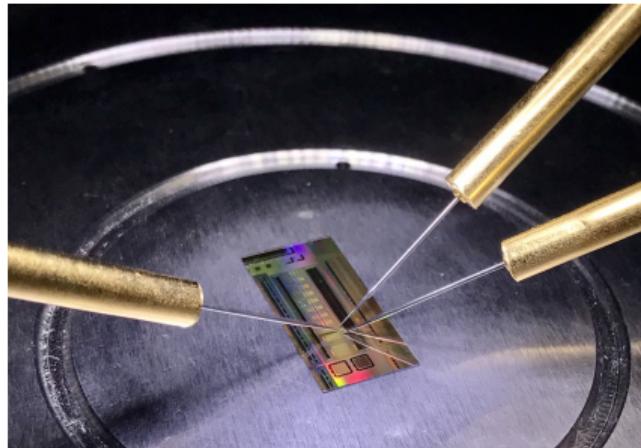
in the meantime... 2 production runs of ARCADIA FD-MAPS.

# ARCADIA passive pixel matrices

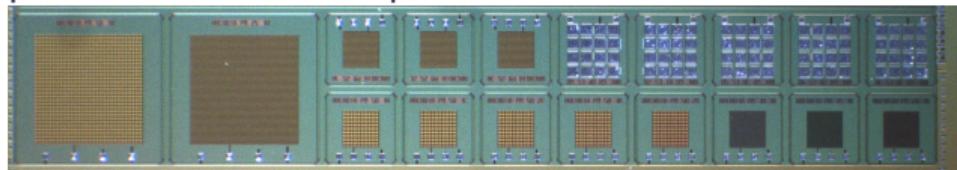
allow electronics independent process validation and tests for pixel design optimizations



Trento Institute for  
Fundamental Physics  
and Applications



picture under microscope:



wafer	wafer type	thickness [μm]
20,22	1	48
3,10	2	100
6,15	3	200

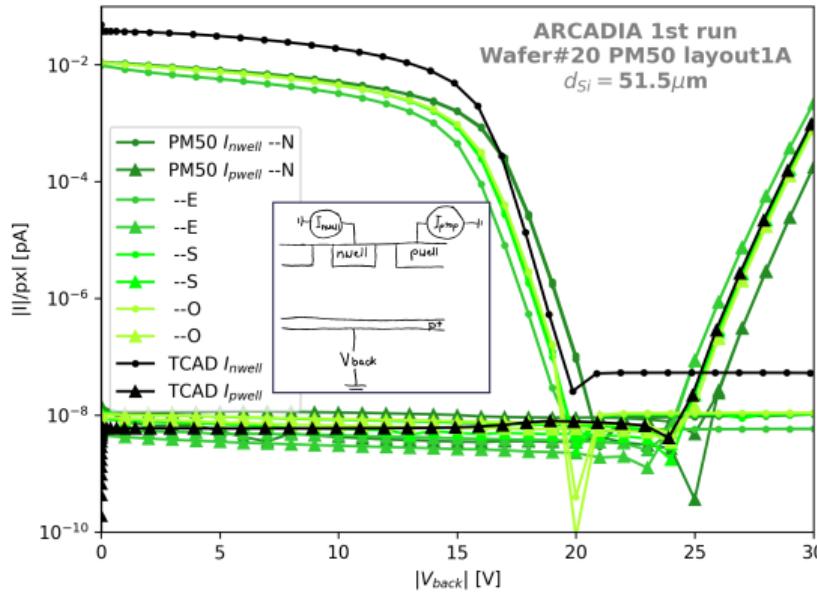
- ▶ two large  $1.5 \times 1.5 \text{ mm}^2$  matrices with pixels of 25 and 50  $\mu\text{m}$  pitch
- ▶ 3/3/5 small  $500 \times 500 \mu\text{m}^2$  matrices with different designs for pixels of 10/25/50  $\mu\text{m}$  pitch
- ▶ each pixel type, one design optimised for low capacitance and one for fast charge collection

pitch [μm]	# layouts
50	5
25	3
10	3

# IV curves used to match simulation to data per wafer



Trento Institute for  
Fundamental Physics  
and Applications



- ▶ uncertainties on doping concentrations, thicknesses and implant accuracies taken to reproduce data

variable	uncertainty*
$N_{sub}$	(42 / 230)%
$d_{Si}$	(- / 8)%
$d_{epi}$	(12 / 14)%

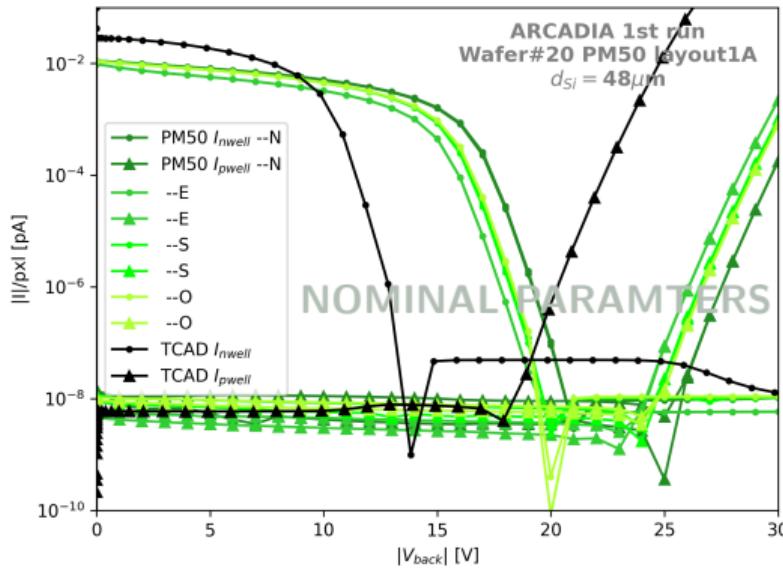
\*given for 2 main wafer types

- ▶ multidimensional parameter space only limited by necessary CPUs for 3D TCAD simulations
- ▶ found good matches of the operating voltage range

# IV curves used to match simulation to data per wafer



Trento Institute for  
Fundamental Physics  
and Applications



- ▶ uncertainties on doping concentrations, thicknesses and implant accuracies taken to reproduce data

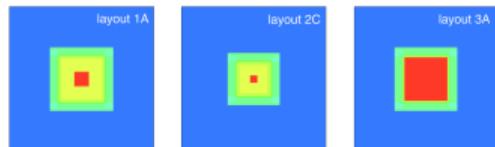
variable	uncertainty*
$N_{sub}$	(42 / 230)%
$d_{Si}$	(- / 8)%
$d_{epi}$	(12 / 14)%

\*given for 2 main wafer types

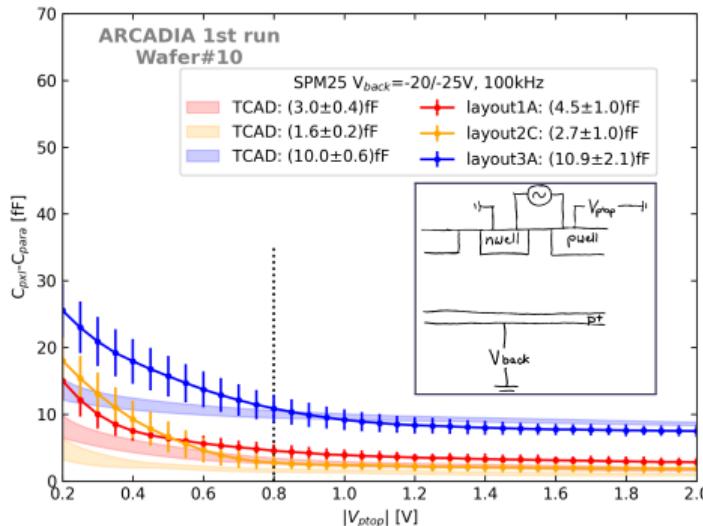
- ▶ multidimensional parameter space only limited by necessary CPUs for 3D TCAD simulations
- ▶ found good matches of the operating voltage range

# CV curves for different pixel designs

$25 \times 25 \mu\text{m}^2$  pixels



Trento Institute for  
Fundamental Physics  
and Applications



- ▶ in simulations observed already at low oxide charge concentrations non-negligible impact on capacitance [1]
- ▶ TCAD simulations include  $N_{ox} = 6.5 \cdot 10^{10} \text{ cm}^{-3}$
- ▶ simulations show too low capacitances, potentially underestimated  $N_{ox}$
- ▶ found oxide charge concentrations with gated diodes on backside of  $1-1.5 \times 10^{12} \text{ cm}^{-3}$  [3], but need estimations of frontside

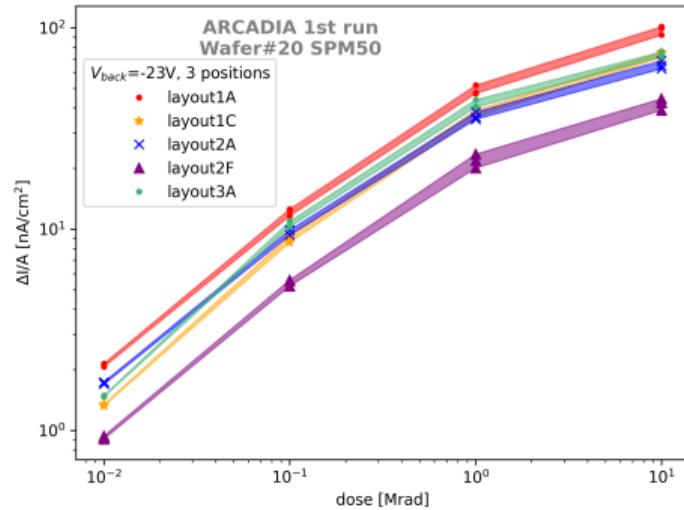
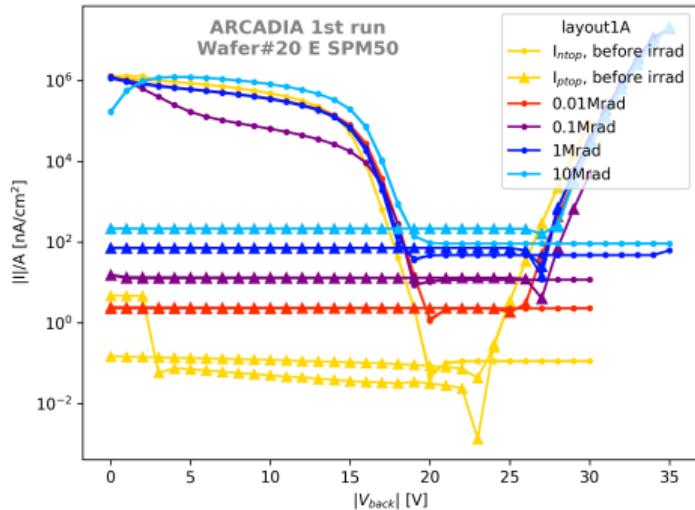
[3] T. Corradino et al., Design and Characterization of Backside Termination Structures for Thick Fully-Depleted MAPS, MDPI Sensors doi:10.3390/s21113809

# Leakage current after x-ray irradiation

together with Uni Padova irradiation campaign with x-ray tube with a Tungsten anode,  
up to a dose of 10Mrad



Trento Institute for  
Fundamental Physics  
and Applications



- ▶ all measurements performed at room temperature
- ▶ after every radiation step, annealing step of 10min@80°C
- ▶ stable operating range
- ▶ non-linear increase of radiation induced leakage currents with possible saturation >1 Mrad

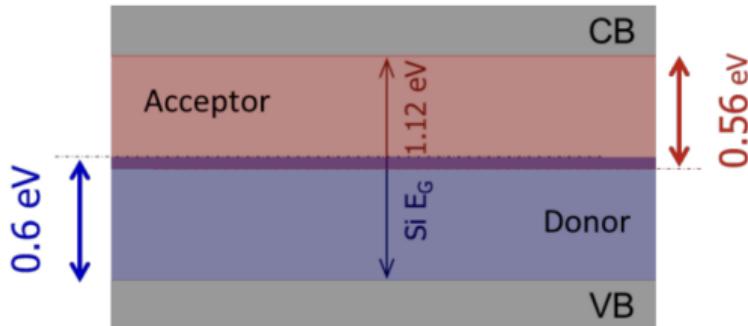
# Modelling of surface damage in TCAD

following New Perugia model [6,7]

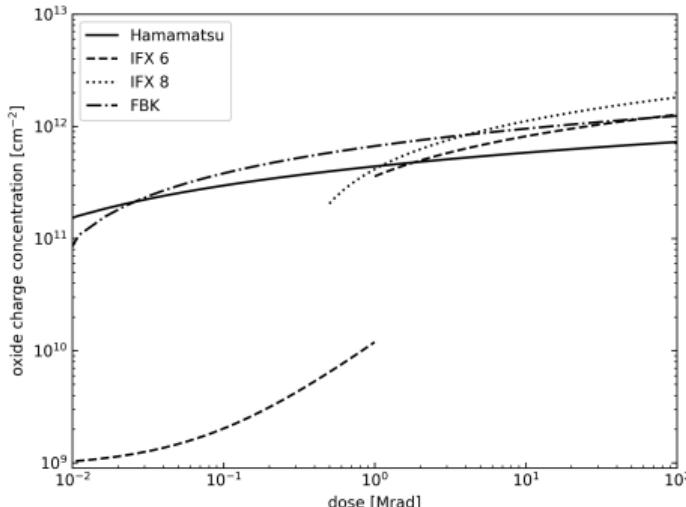


Trento Institute for  
Fundamental Physics  
and Applications

- included positive oxide charge, and 1 acceptor + 1 donor trap



- parametrized on p-type Si from different producers; Hamamatsu, Infineon, FBK
- data points from 50 krad-100 Mrad



► oxide charge  $(1 \cdot 10^9 - 8 \cdot 10^{10}) \text{ cm}^{-2}$  at 0 dose

[6] AIDA2020 report,

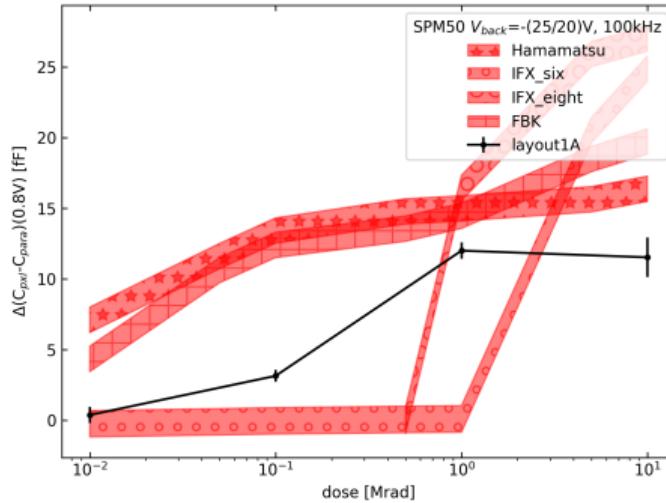
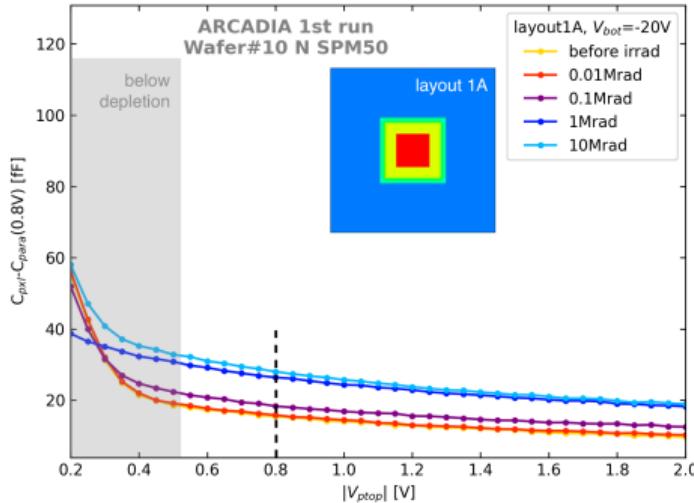
[7] A. Morozzi et al., TCAD Modeling of Surface Radiation Damage Effects: A State-Of-The-Art Review, *Frontiers in Physics*  
doi:10.3389/fphy.2021.617322

# CV curves before/after irradiation

50×50  $\mu\text{m}^2$  pixels



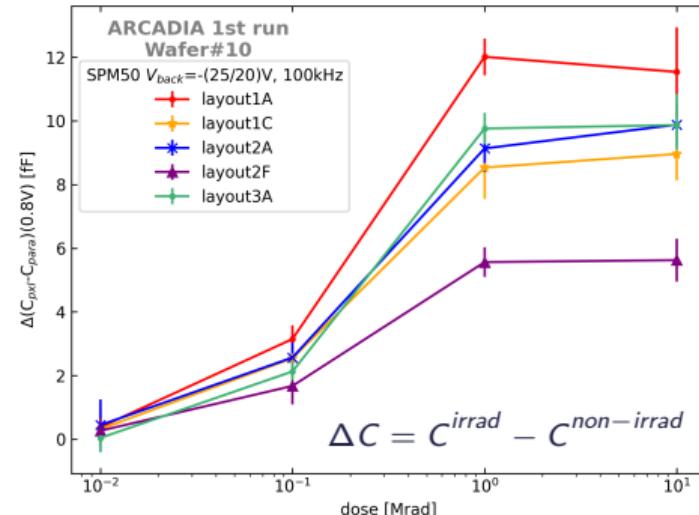
Trento Institute for  
Fundamental Physics  
and Applications



- ▶ impact of surface damage on capacitance clearly visible
  - ▶ capacitance almost doubles after 10Mrad, starting from 15fF before irradiation
  - ▶ comparison with simulation: none of the models describes the data over full dose range
- included new test-structures in next ARCADIA run to determine trap and oxide charge concentrations for new parameterisation

# Capacitance increase for different pixel designs

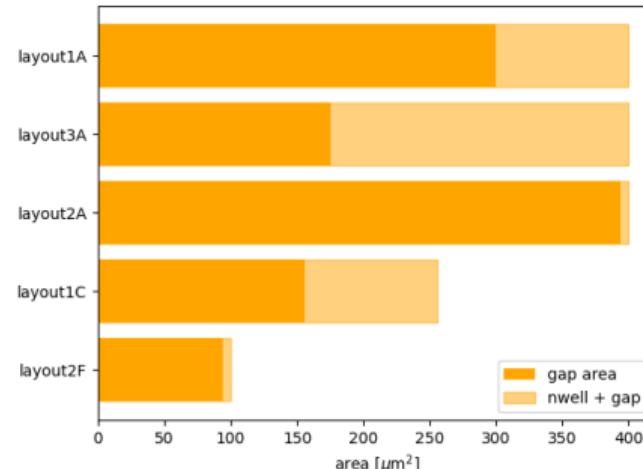
50×50  $\mu\text{m}^2$  pixels



- absolute capacitance increase of up to 12 fF/pixel



Trento Institute for  
Fundamental Physics  
and Applications



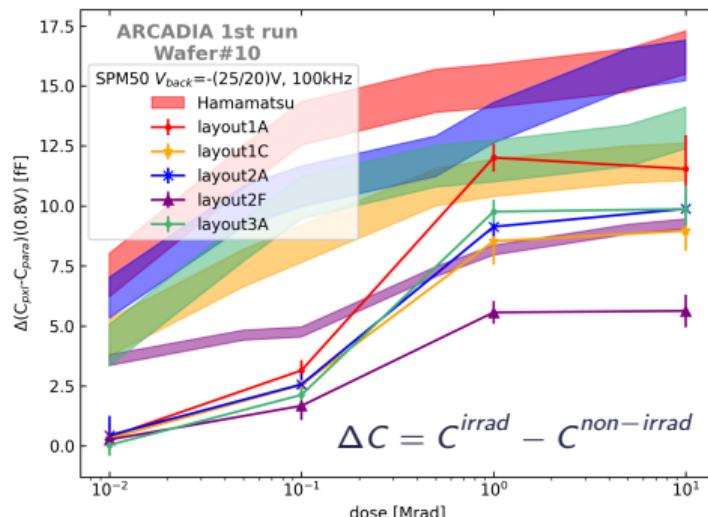
- layouts differ in collection node size and gap between n and pwell
- increase of the capacitance is clearly correlated with pwell-free area

# Capacitance increase for different pixel designs

50×50  $\mu\text{m}^2$  pixels



Trento Institute for  
Fundamental Physics  
and Applications



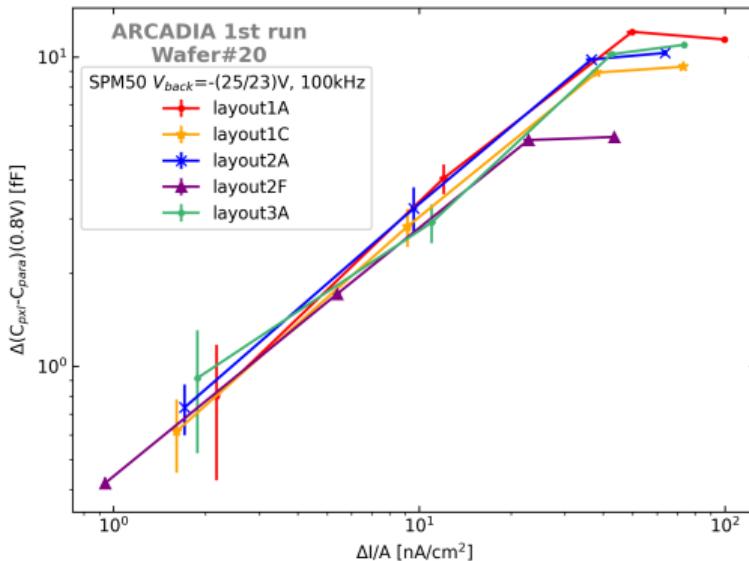
- ▶ Hamamatsu parametrisation predicts earlier and stronger increase of capacitance
- ▶ good reproduction of the impact of the designs on capacitance
- ▶ layout optimised for low capacitance before irradiation, shows smallest impact of surface damage after irradiation

# Capacitance-current increase correlation

50×50  $\mu\text{m}^2$  pixels



Trento Institute for  
Fundamental Physics  
and Applications



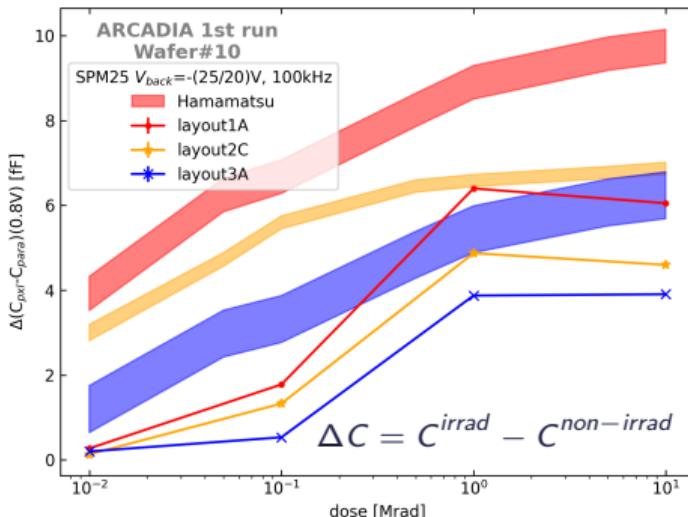
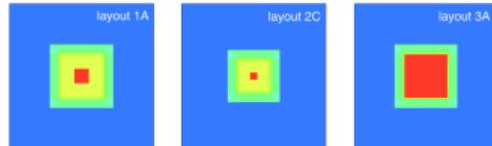
- ▶ clear correlation between capacitance and leakage current increase
- ▶ all layouts show similar relationship, except for saturation in capacitance which is observed at different stages of leakage increase

# Capacitance increase for different pixel designs

$25 \times 25 \mu\text{m}^2$  pixels



Trento Institute for  
Fundamental Physics  
and Applications



- ▶ similar results on matrices with smaller pixel pitch

potentially interesting design of small capacitance (layout 2C):

- ▶ 3 fF/pixel before irradiation
- ▶ smaller increase after irradiation compared to *default* pixel (layout 1A), currently in use in main demonstrator (MD) chip
- ▶ slower charge collection at edges

# Conclusions



Trento Institute for  
Fundamental Physics  
and Applications

- ▶ ARCADIA collaboration successfully produced functional sensors in first 2 production runs
- ▶ method to adjust TCAD inputs per wafer established and good agreement with measurements achieved
- ▶ surface damage non-negligible impact on pixel capacitances, main trends of impact of positive oxide charges validated with data
- ▶ radiation damage model needs technology-optimised parametrisation
  - gated diodes and MOS capacitors included in 3rd ARCADIA run for characterisation and parameter determination

# Conclusions



Trento Institute for  
Fundamental Physics  
and Applications

- ▶ ARCADIA collaboration successfully produced functional sensors in first 2 production runs
- ▶ method to adjust TCAD inputs per wafer established and good agreement with measurements achieved
- ▶ surface damage non-negligible impact on pixel capacitances, main trends of impact of positive oxide charges validated with data
- ▶ radiation damage model needs technology-optimised parametrisation
  - gated diodes and MOS capacitors included in 3rd ARCADIA run for characterisation and parameter determination

THANK YOU FOR YOUR ATTENTION!

# ARCADIA collaboration

INFN - Bologna, Milano, Padova, Perugia, Pavia, TIFPA, Torino



Trento Institute for  
Fundamental Physics  
and Applications

Many thanks!

F. Alfonsi, G. Ambrosi, A. Andreazza, G. Andolini, E. Bianco, G. Balbi, M. Barbanera, S. Beole, C. Bonini, J. Cai, M. Caccia, A. Candelori, D. Chiappara, F. Cossio, S. Cometti, **Thomas Corradino**, T. Croci, M. Da Rocha Rolo, G. F. Dalla Betta, A. De Angelis, G. Dellacasa, N. Demaria, L. De Cilladi, B. Di Ruzza, A. Di Salvo, S. Durando, D. Falchieri, C. Ferrero, A. Gabrielli, L. Gaioni, S. Garbolino, G. Gebbia, R. A. Giampaolo, N. Giangiacomi , P. Giubilato, R. Iuppa, M. Mandurrino, M. Manghisoni, M. Mignone, **Serena Mattiazzo**, C. Neubuser, F. Nozzoli, **Lucio Pancheri**, D. Passeri, A. Paterno, M. Pezzoli, P. Placidi, **Harvey M. Postlethwaite**, L. Ratti, E. Ricci, S. B. Ricciarini, A. Rivetti, R. Santoro, L. Servoli, S. Tedesco, G. Torilla, G. Traversi, C. Vacchi, R. Wheaton, J. Wyss, P. Zuccon

# BACKUP

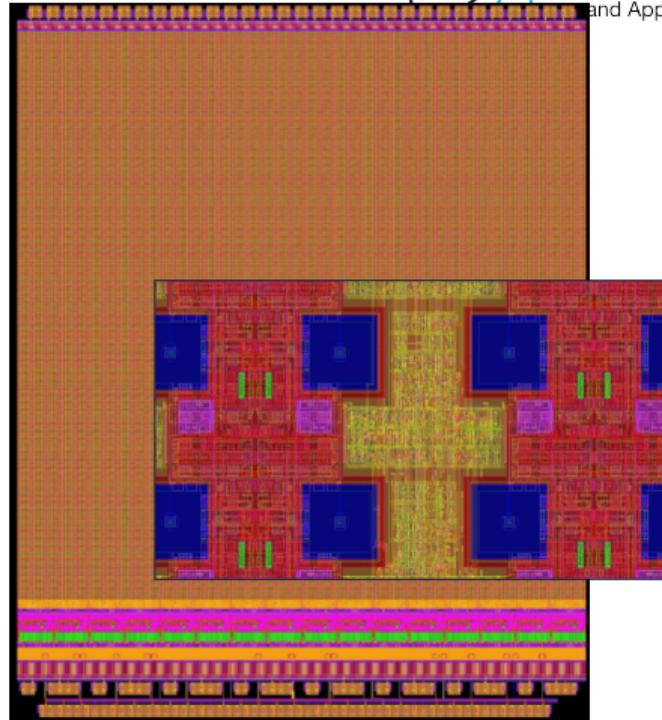
# ARCADIA MD1 – specs

trigger-less, and binary readout



Trento Institute for  
Fundamental Physics  
and Applications

- ▶ matrix core  $512 \times 512$  pxls of  $25 \mu\text{m}$  pitch
- ▶ pixels are  $\sim(50/50)\%$  analog/digital
- ▶ sensor diode about 20% of total area
- ▶ clock-less matrix (to minimize power dissipation)
- ▶ pixel regions propagate the output data to the periphery



*Manuel Rolo, INFN Torino*